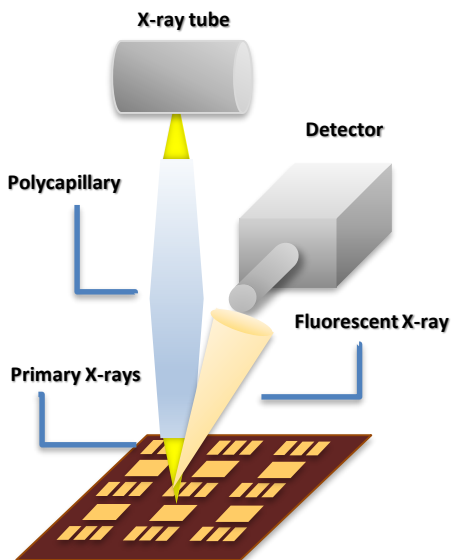


Fluorescent X-ray Coating Thickness Gauge FT160 Series

FT160S, FT160h, FT160L / FT160Sh, FT160h, FT160Lh

Latest in high end XRF coating thickness measurement. High precision, high throughput at nano-order level plating applied to small, microscopic electronic components, featuring a polycapillary optic system and high count rate semiconductor detector.

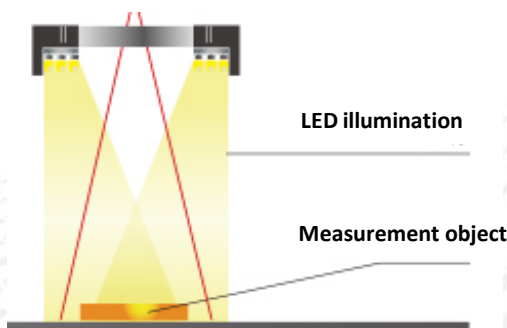
■ Features of FT160 Series



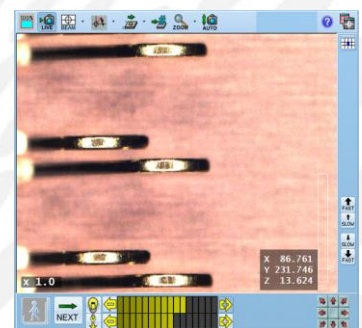
- **Polycapillary X-ray optic system.**
Implementing a 30 $\mu\text{m}\phi$ high intensity primary X-ray beam for high precision measurement.
- **High performance semi conductor detector (SDD).**
Employing a high count rate semiconductor (SDD) for high precision measurement.
- **Auto measure assist through image processing software.**
Accurate multi-point auto measurement capability for high efficiency.
- **Simple operation by simple software design and help function.**
Register measure method as app. Easy daily measure routine.
- **Operator safety-minded design.**
Sealed housing for extremely low risk of X-ray leakage.
Large door opening for sample visibility and operability.

■ Improved visibility of samples

Samples shaped with bumps or terminal contacts may be difficult to position the point of measurement depending on how sample observation illumination is aligned. FT160 redesigned illumination improves sample visibility.



Conventional



FT160 Series

Simple software for better usability 「XRF Controller」

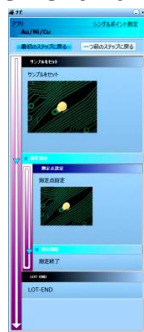
【Launcher Screen】

Select application from large icons.



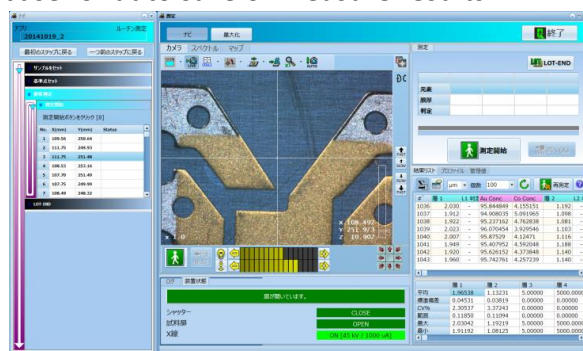
【Navigation Screen】

Verify next operation with Measurement Navigation.



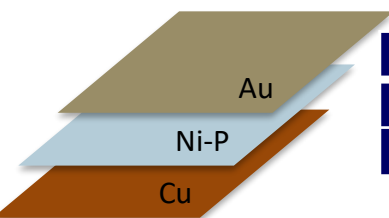
【Sample Screen】

Verify next operation with Micro sample positioning and easy sample imaging. Data base for auto save of measure results.



Measurement example of electroless Ni (EN) and gold (IG) on print board by FT160

Measurement result of 30 repetitions of ENIG plating and composition



FT160 conditions		Average	Au (μm)	Ni-P (μm)	P (wt%)
Method	Film FP	SD	0.094	3.25	8.52
Time	100 S	RSD (%)	0.001	0.01	0.35
			0.8	0.5	4.1

FT160 Series Basic Specifications

Exterior



Model	FT160S	FT160Sh	FT160	FT160h	FT160L	FT160Lh
Tube target	Mo	W	Mo	W	Mo	W
Targeted elements	¹³ Al to ⁹² U		¹³ Al to ⁹² U		¹³ Al to ⁹² U	
Dimensions (mm)	690(W) × 900(D) × 710(H)		930(W) × 900(D) × 710(H)		1030(W) × 1260(D) × 710(H)	
Stage (mm)	300(W) × 245(D)		420(W) × 320(D)		620(W) × 620(D)	
Weight (kg)	150		160		175	
Stroke (mm)	300(X) × 260(Y)		400(X) × 300(Y)		300(X) × 300(Y)	
Measurable size	300(X) × 245(Y) × 80(Z) (mm)		400(X) × 300(Y) × 100(Z) (mm)		600(X) × 600(Y) × 20(Z) (mm)	

Safety caution

In order to use product safely, be sure to read the operation manual first.

Notification of X-ray device installation

Notification of installation must be submitted to relevant labor standards inspection office 30 days before installation when installing an X-ray device.



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